

IN THE CLAIMS

Please amend the claims as follows:

1. (Currently amended) A method of fabricating a vacuum microtube device comprising the steps of:

forming a cathode layer comprising an array of carbon nanotube electron emitters;

forming a separate gate layer comprising an array of openings for passing electrons from the electron emitters;

forming a separate an anode layer comprising an array of anodes for receiving electrons; and

vertically aligning and spacing the cathode layer, the gate layer and the anode layer and then bonding them together on a substrate comprising silicon so that electrons from the emitters pass through the gate openings to the anode.

2. (Original) The method of claim 1 wherein the cathode layer comprises silicon.

3. (Currently amended) The method of claim 1 wherein the cathode layer, the gate layer and the anode layer are bonded together with one or more intervening spacers.

4. (Original) The method of claim 1 further comprising the step of disposing between the gate layer and the anode, an electron multiplying structure comprising secondary electron emission material in the path of emitted electrons for multiplying the electron flow between the cathode and the anode.

5-12. (Canceled)